EFS ID: 1120591	
Application Number: 10790492	
Confirmation Number: 9512	
Title of Invention: Atomic layer deposition of capacitor dielectric	
First Named Inventor: Lingyi A. Zheng	
DINSMORE & SHOHL LLP One Dayton Centre Suite 500 Correspondence Address: One South Main Street Dayton OH 45402- US 9372230724	2023
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Document Number	Document Description	File Name	File Size(Bytes)	Multi Part	Pages
1	Amendment - After Non-Final Rejection	MIO0082N2amendment.pdf	386864	no	10
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National Stage of an International Application under 35 U.S.C. 371

If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.